

# Shiyuan Liu

## List of Publications by Year in descending order

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198  
papers

3,514  
citations

186265

28  
h-index

189892

50  
g-index

199  
all docs

199  
docs citations

199  
times ranked

3743  
citing authors

#	ARTICLE	IF	CITATIONS
1	2D Layered Materialâ€Based van der Waals Heterostructures for Optoelectronics. <i>Advanced Functional Materials</i> , 2018, 28, 1706587.	14.9	279
2	A level set solution to the stress-based structural shape and topology optimization. <i>Computers and Structures</i> , 2012, 90-91, 55-64.	4.4	167
3	Highâ€Performance Polymer Tandem Solar Cells Employing a New nâ€Type Conjugated Polymer as an Interconnecting Layer. <i>Advanced Materials</i> , 2016, 28, 4817-4823.	21.0	156
4	Development of a broadband Mueller matrix ellipsometer as a powerful tool for nanostructure metrology. <i>Thin Solid Films</i> , 2015, 584, 176-185.	1.8	121
5	Synthesis of a nanowire self-assembled hierarchical ZnCo <sub>2</sub> O <sub>4</sub> shell/Ni current collector core as binder-free anodes for high-performance Li-ion batteries. <i>Journal of Materials Chemistry A</i> , 2014, 2, 3741-3748.	10.3	91
6	Beyond the Thermal Equilibrium Limit of Ammonia Synthesis with Dual Temperature Zone Catalyst Powered by Solar Light. <i>CheM</i> , 2019, 5, 2702-2717.	11.7	91
7	A level set based method for the optimization of cast part. <i>Structural and Multidisciplinary Optimization</i> , 2010, 41, 735-747.	3.5	88
8	Strong Second- and Third-Harmonic Generation in 1D Chiral Hybrid Bismuth Halides. <i>Journal of the American Chemical Society</i> , 2021, 143, 16095-16104.	13.7	74
9	Broadband optical properties of graphene and HOPG investigated by spectroscopic Mueller matrix ellipsometry. <i>Applied Surface Science</i> , 2018, 439, 1079-1087.	6.1	67
10	Overcoming Spaceâ€Charge Effect for Efficient Thickâ€Film Nonâ€Fullerene Organic Solar Cells. <i>Advanced Energy Materials</i> , 2018, 8, 1801609.	19.5	62
11	Optical Analysis for Semitransparent Organic Solar Cells. <i>Solar Rrl</i> , 2019, 3, 1800270.	5.8	62
12	Layerâ€Dependent Dielectric Function of Waferâ€Scale 2D MoS <sub>2</sub> . <i>Advanced Optical Materials</i> , 2019, 7, 1801250.	7.3	58
13	Efficient source and mask optimization with augmented Lagrangian methods in optical lithography. <i>Optics Express</i> , 2013, 21, 8076.	3.4	55
14	Layer-dependent dielectric and optical properties of centimeter-scale 2D WSe <sub>2</sub> : evolution from a single layer to few layers. <i>Nanoscale</i> , 2019, 11, 22762-22771.	5.6	55
15	Optimal broadband Mueller matrix ellipsometer using multi-waveplates with flexibly oriented axes. <i>Journal of Optics (United Kingdom)</i> , 2016, 18, 025702.	2.2	52
16	24.1% External Quantum Efficiency of Flexible Quantum Dot Lightâ€Emitting Diodes by Light Extraction of Silver Nanowire Transparent Electrodes. <i>Advanced Optical Materials</i> , 2018, 6, 1800347.	7.3	51
17	To improve the efficiency of thermally activated delayed fluorescence OLEDs by controlling the horizontal orientation through optimizing stereoscopic and linear structures of indolocarbazole isomers. <i>Journal of Materials Chemistry C</i> , 2018, 6, 5812-5820.	5.5	49
18	Mueller matrix imaging ellipsometry for nanostructure metrology. <i>Optics Express</i> , 2015, 23, 17316.	3.4	48

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19	Determination of Dielectric Functions and Exciton Oscillator Strength of Two-Dimensional Hybrid Perovskites. , 2021, 3, 148-159.		47
20	Highly Efficient Tandem Organic Solar Cell Enabled by Environmentally Friendly Solvent Processed Polymeric Interconnecting Layer. Advanced Energy Materials, 2018, 8, 1703180.	19.5	44
21	Ultrathin Polymer Nanofibrils for Solar-Blind Deep Ultraviolet Light Photodetectors Application. Nano Letters, 2020, 20, 644-651.	9.1	38
22	Detection of engine valve faults by vibration signals measured on the cylinder head. Proceedings of the Institution of Mechanical Engineers, Part D: Journal of Automobile Engineering, 2006, 220, 379-386.	1.9	36
23	Level-set-based inverse lithography for mask synthesis using the conjugate gradient and an optimal time step. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2013, 31, .	1.2	36
24	Estimation of the convergence order of rigorous coupled-wave analysis for binary gratings in optical critical dimension metrology. Optical Engineering, 2012, 51, 081504.	1.0	35
25	Accurate characterization of nanoimprinted resist patterns using Mueller matrix ellipsometry. Optics Express, 2014, 22, 15165.	3.4	35
26	Complex Optical Conductivity of Two-Dimensional MoS <sub>2</sub> : A Striking Layer Dependency. Journal of Physical Chemistry Letters, 2019, 10, 6246-6252.	4.6	35
27	Shape and topology optimization for tailoring stress in a local region to enhance performance of piezoresistive sensors. Computers and Structures, 2013, 114-115, 98-105.	4.4	30
28	Measurement configuration optimization for accurate grating reconstruction by Mueller matrix polarimetry. Journal of Micro/ Nanolithography, MEMS, and MOEMS, 2013, 12, 033013.	0.9	30
29	Depolarization effects from nanoimprinted grating structures as measured by Mueller matrix polarimetry. Applied Physics Letters, 2013, 103, .	3.3	29
30	Layer-dependent dielectric permittivity of topological insulator Bi <sub>2</sub> Se <sub>3</sub> thin films. Applied Surface Science, 2020, 509, 144822.	6.1	29
31	Improved model-based infrared reflectometry for measuring deep trench structures. Journal of the Optical Society of America A: Optics and Image Science, and Vision, 2009, 26, 2327.	1.5	28
32	Improved measurement accuracy in optical scatterometry using correction-based library search. Applied Optics, 2013, 52, 6726.	1.8	28
33	Formulation of error propagation and estimation in grating reconstruction by a dual-rotating compensator Mueller matrix polarimeter. Thin Solid Films, 2014, 571, 653-659.	1.8	27
34	Aerial image based technique for measurement of lens aberrations up to 37th Zernike coefficient in lithographic tools under partial coherent illumination. Optics Express, 2009, 17, 19278.	3.4	25
35	Robust solution to the inverse problem in optical scatterometry. Optics Express, 2014, 22, 22031.	3.4	25
36	Calibration of misalignment errors in composite waveplates using Mueller matrix ellipsometry. Applied Optics, 2015, 54, 684.	1.8	25

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37	Preparation of transparent MgO·1.8Al <sub>2</sub> O <sub>3</sub> spinel ceramics by aqueous gelcasting, presintering and hot isostatic pressing. <i>Journal of the European Ceramic Society</i> , 2018, 38, 4057-4063.	5.7	25
38	A novel spinel-type Mg <sub>0.55</sub> Al <sub>2.36</sub> O <sub>3.81</sub> N <sub>0.19</sub> transparent ceramic with infrared transmittance range comparable to c-plane sapphire. <i>Scripta Materialia</i> , 2020, 178, 428-432.	5.2	25
39	Optical wafer defect inspection at the 10 nm technology node and beyond. <i>International Journal of Extreme Manufacturing</i> , 2022, 4, 032001.	12.7	25
40	Nanopatterning Technologies of 2D Materials for Integrated Electronic and Optoelectronic Devices. <i>Advanced Materials</i> , 2022, 34, e2200734.	21.0	25
41	Simultaneous optimization of cast part and parting direction using level set method. <i>Structural and Multidisciplinary Optimization</i> , 2011, 44, 751-759.	3.5	24
42	Comprehensive characterization of a general composite waveplate by spectroscopic Mueller matrix polarimetry. <i>Optics Express</i> , 2018, 26, 25408.	3.4	24
43	Study of the retardance of a birefringent waveplate at tilt incidence by Mueller matrix ellipsometer. <i>Journal of Optics (United Kingdom)</i> , 2018, 20, 015401.	2.2	23
44	Depolarization artifacts in dual rotating-compensator Mueller matrix ellipsometry. <i>Journal of Optics (United Kingdom)</i> , 2016, 18, 055701.	2.2	22
45	Flexible Perovskite Solar Cells via Surface-Confined Silver Nanoparticles on Transparent Polyimide Substrates. <i>Polymers</i> , 2019, 11, 427.	4.5	22
46	Complete Dielectric Tensor and Giant Optical Anisotropy in Quasi-One-Dimensional ZrTe <sub>5</sub> . <i>Nanoscale</i> , 2021, 3, 525-534.		22
47	Fabrication of the similar porous alumina silicon template for soft UV nanoimprint lithography. <i>Applied Surface Science</i> , 2013, 276, 363-368.	6.1	21
48	Porous Light-Emitting Diodes With Patterned Sapphire Substrates Realized by High-Voltage Self-Growth and Soft UV Nanoimprint Processes. <i>Journal of Lightwave Technology</i> , 2014, 32, 326-332.	4.6	21
49	Development of a spectroscopic Mueller matrix imaging ellipsometer for nanostructure metrology. <i>Review of Scientific Instruments</i> , 2016, 87, 053707.	1.3	21
50	Improved measurement accuracy in optical scatterometry using fitting error interpolation based library search. <i>Measurement: Journal of the International Measurement Confederation</i> , 2013, 46, 2638-2646.	5.0	20
51	Determination of an optimal measurement configuration in optical scatterometry using global sensitivity analysis. <i>Thin Solid Films</i> , 2014, 562, 16-23.	1.8	20
52	Evaporable Glass-State Molecule-Assisted Transfer of Clean and Intact Graphene onto Arbitrary Substrates. <i>ACS Applied Materials &amp; Interfaces</i> , 2019, 11, 16272-16279.	8.0	20
53	Imaging Mueller matrix ellipsometry with sub-micron resolution based on back focal plane scanning. <i>Optics Express</i> , 2021, 29, 32712.	3.4	20
54	Modeling the formation of spontaneous wafer direct bonding under low temperature. <i>Microelectronic Engineering</i> , 2008, 85, 1754-1757.	2.4	19

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55	Mueller matrix ellipsometric detection of profile asymmetry in nanoimprinted grating structures. <i>Journal of Applied Physics</i> , 2014, 116, 194305.	2.5	19
56	Efficient source mask optimization with Zernike polynomial functions for source representation. <i>Optics Express</i> , 2014, 22, 3924.	3.4	19
57	Effect of nanoscale surface topography on low temperature direct wafer bonding process with UV activation. <i>Sensors and Actuators A: Physical</i> , 2009, 151, 81-86.	4.1	18
58	Efficient light-driven CO <sub>2</sub> hydrogenation on Ru/CeO <sub>2</sub> catalysts. <i>Catalysis Science and Technology</i> , 2018, 8, 6503-6510.	4.1	18
59	An analytical method to determine the complex refractive index of an ultra-thin film by ellipsometry. <i>Applied Surface Science</i> , 2020, 507, 145091.	6.1	18
60	High-speed Mueller matrix ellipsometer with microsecond temporal resolution. <i>Optics Express</i> , 2020, 28, 10873.	3.4	18
61	Identification and reconstruction of diffraction structures in optical scatterometry using support vector machine method. <i>Journal of Micro/ Nanolithography, MEMS, and MOEMS</i> , 2013, 12, 013004.	0.9	17
62	Birefringence and Dichroism in Quasi-1D Transition Metal Trichalcogenides: Direct Experimental Investigation. <i>Small</i> , 2021, 17, e2100457.	10.0	17
63	Accurate alignment of optical axes of a biplate using a spectroscopic Mueller matrix ellipsometer. <i>Applied Optics</i> , 2016, 55, 3935.	2.1	16
64	Highly transparent Mg <sub>0.27</sub> Al <sub>2.58</sub> O <sub>3.73</sub> N <sub>0.27</sub> ceramic fabricated by aqueous gelcasting, pressureless sintering, and post-CHIP. <i>Journal of the American Ceramic Society</i> , 2019, 102, 6507-6516.	3.8	16
65	Giant Gate-Tunability of Complex Refractive Index in Semiconducting Carbon Nanotubes. <i>ACS Photonics</i> , 2020, 7, 2896-2905.	6.6	16
66	Simulation method for study on outcoupling characteristics of stratified anisotropic OLEDs. <i>Optics Express</i> , 2019, 27, A1014.	3.4	16
67	Mask-filtering-based inverse lithography. <i>Journal of Micro/ Nanolithography, MEMS, and MOEMS</i> , 2013, 12, 043003.	0.9	15
68	Calibration of polarization effect of a high-numerical-aperture objective lens with Mueller matrix polarimetry. <i>Measurement Science and Technology</i> , 2019, 30, 025201.	2.6	15
69	Effect of nitrogen content on optical properties of transparent $\hat{3}$ -AlON polycrystalline ceramics. <i>Journal of the European Ceramic Society</i> , 2021, 41, 4319-4326.	5.7	15
70	Gearbox condition monitoring using self-organizing feature maps. <i>Proceedings of the Institution of Mechanical Engineers, Part C: Journal of Mechanical Engineering Science</i> , 2004, 218, 119-129.	2.1	14
71	Improved deep-etched multilayer grating reconstruction by considering etching anisotropy and abnormal errors in optical scatterometry. <i>Optics Letters</i> , 2015, 40, 471.	3.3	14
72	All-dielectric metasurface-based roll-angle sensor. <i>Sensors and Actuators A: Physical</i> , 2018, 279, 509-517.	4.1	14

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73	The on-line detection of engine misfire at low speed using multiple feature fusion with fuzzy pattern recognition. Proceedings of the Institution of Mechanical Engineers, Part D: Journal of Automobile Engineering, 2002, 216, 391-402.	1.9	12
74	An optimized process for fabrication of high-aspect-ratio photoresist-derived carbon microelectrode array on silicon substrate. Thin Solid Films, 2010, 518, 2701-2706.	1.8	12
75	High-throughput dielectrophoretic manipulation of bioparticles within fluids through biocompatible three-dimensional microelectrode array. Electrophoresis, 2011, 32, 494-505.	2.4	12
76	Robust and efficient inverse mask synthesis with basis function representation. Journal of the Optical Society of America A: Optics and Image Science, and Vision, 2014, 31, B1.	1.5	12
77	(Invited) Mueller Matrix Polarimetry: A Powerful Tool for Nanostructure Metrology. ECS Transactions, 2014, 60, 237-242.	0.5	12
78	Towards understanding the detection of profile asymmetry from Mueller matrix differential decomposition. Journal of Applied Physics, 2015, 118, .	2.5	12
79	2D Niobium-Doped MoS <sub>2</sub> : Tuning the Exciton Transitions and Potential Applications. ACS Applied Electronic Materials, 2021, 3, 2564-2572.	4.3	12
80	Machine learning aided solution to the inverse problem in optical scatterometry. Measurement: Journal of the International Measurement Confederation, 2022, 191, 110811.	5.0	12
81	Generalized formulations for aerial image based lens aberration metrology in lithographic tools with arbitrarily shaped illumination sources. Optics Express, 2010, 18, 20096.	3.4	11
82	Characterization of curved surface layer by Mueller matrix ellipsometry. Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics, 2016, 34, .	1.2	11
83	Characterization of beam splitters in the calibration of a six-channel Stokes polarimeter. Journal of Optics (United Kingdom), 2018, 20, 125606.	2.2	11
84	Development of a tomographic Mueller-matrix scatterometer for nanostructure metrology. Review of Scientific Instruments, 2018, 89, 073702.	1.3	11
85	Eigenvalue calibration method for dual rotating-compensator Mueller matrix polarimetry. Optics Letters, 2021, 46, 4618.	3.3	11
86	Fitting-determined formulation of effective medium approximation for 3D trench structures in model-based infrared reflectometry. Journal of the Optical Society of America A: Optics and Image Science, and Vision, 2011, 28, 263.	1.5	10
87	Fast aerial image simulations for partially coherent systems by transmission cross coefficient decomposition with analytical kernels. Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics, 2012, 30, .	1.2	10
88	Tailoring diffraction-induced light distribution toward controllable fabrication of suspended C-MEMS. Optics Express, 2012, 20, 17126.	3.4	10
89	Optimization of stresses in a local region for the maximization of sensitivity and minimization of cross-sensitivity of piezoresistive sensors. Structural and Multidisciplinary Optimization, 2013, 48, 927-938.	3.5	10
90	Cascadic multigrid algorithm for robust inverse mask synthesis in optical lithography. Journal of Micro/ Nanolithography, MEMS, and MOEMS, 2014, 13, 023003.	0.9	10

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91	Illumination source optimization in optical lithography via derivative-free optimization. <i>Journal of the Optical Society of America A: Optics and Image Science, and Vision</i> , 2014, 31, B19.	1.5	10
92	Characterization of dielectric function for metallic thin films based on ellipsometric parameters and reflectivity. <i>Physica Scripta</i> , 2019, 94, 085802.	2.5	10
93	Investigation of Spatial Chirp Induced by Misalignments in a Parallel Grating Pair Pulse Stretcher. <i>Applied Sciences (Switzerland)</i> , 2020, 10, 1584.	2.5	10
94	Complex optical conductivity of Bi <sub>2</sub> Se <sub>3</sub> thin film: Approaching two-dimensional limit. <i>Applied Physics Letters</i> , 2021, 118, .	3.3	10
95	Fast algorithm for quadratic aberration model in optical lithography based on cross triple correlation. <i>Journal of Micro/ Nanolithography, MEMS, and MOEMS</i> , 2011, 10, 023007.	0.9	9
96	Nondestructive analysis of lithographic patterns with natural line edge roughness from Mueller matrix ellipsometric data. <i>Applied Surface Science</i> , 2016, 388, 524-530.	6.1	9
97	Application of measurement configuration optimization for accurate metrology of sub-wavelength dimensions in multilayer gratings using optical scatterometry. <i>Applied Optics</i> , 2016, 55, 6844.	2.1	9
98	Metrology of Nanostructures by Tomographic Mueller-Matrix Scatterometry. <i>Applied Sciences (Switzerland)</i> , 2018, 8, 2583.	2.5	9
99	Iterative method for in situ measurement of lens aberrations in lithographic tools using CTC-based quadratic aberration model. <i>Optics Express</i> , 2012, 20, 14272.	3.4	8
100	Strain-optical behavior of polyethylene terephthalate film during uniaxial stretching investigated by Mueller matrix ellipsometry. <i>Polymer</i> , 2019, 182, 121842.	3.8	8
101	Proof of principle of an optical Stokes absolute roll-angle sensor with ultra-large measuring range. <i>Sensors and Actuators A: Physical</i> , 2019, 291, 144-149.	4.1	8
102	Nondestructive investigation on the nanocomposite ordering upon holography using Mueller matrix ellipsometry. <i>European Polymer Journal</i> , 2019, 110, 123-129.	5.4	8
103	Thickness dependent native oxidation kinetics observation and prediction for Cu films using spectroscopic ellipsometry. <i>Applied Surface Science</i> , 2020, 518, 146236.	6.1	8
104	Unsupervised learning polarimetric underwater image recovery under nonuniform optical fields. <i>Applied Optics</i> , 2021, 60, 8198.	1.8	8
105	Performance optimization of tandem organic solar cells at varying incident angles based on optical analysis method. <i>Optics Express</i> , 2020, 28, 2381.	3.4	8
106	Optical and electronic anisotropy of a 2D semiconductor SiP. <i>Nano Research</i> , 2022, 15, 8579-8586.	10.4	8
107	Convolution-variation separation method for efficient modeling of optical lithography. <i>Optics Letters</i> , 2013, 38, 2168.	3.3	7
108	Fabrication and Properties of Dual-Level Hierarchical Structures Mimicking Gecko Foot Hairs. <i>Journal of Nanoscience and Nanotechnology</i> , 2013, 13, 781-786.	0.9	7

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109	Ellipsometry study on Pd thin film grown by atomic layer deposition with Maxwell's Garnett effective medium approximation model. <i>Thin Solid Films</i> , 2015, 593, 144-149.	1.8	7
110	Probing optimal measurement configuration for optical scatterometry by the multi-objective genetic algorithm. <i>Measurement Science and Technology</i> , 2018, 29, 045014.	2.6	7
111	Remote Absolute Roll-Angle Measurement in Range of 180° Based on Polarization Modulation. <i>Nanomanufacturing and Metrology</i> , 2020, 3, 228-235.	3.0	7
112	Molecular Understanding of Electrochemical-Mechanical Responses in Carbon-Coated Silicon Nanotubes during Lithiation. <i>Nanomaterials</i> , 2021, 11, 564.	4.1	7
113	Reconstruction of finite deep sub-wavelength nanostructures by Mueller-matrix scattered-field microscopy. <i>Optics Express</i> , 2021, 29, 32158.	3.4	7
114	A Novel Technique for Data Visualization Based on SOM. <i>Lecture Notes in Computer Science</i> , 2005, , 421-426.	1.3	7
115	Thickness and Layer Stacking Order Effects on Complex Optical Conductivity and Exciton Strength of Few-Layer Graphene: Implications for Optical Modulators and Photodetectors. <i>ACS Applied Nano Materials</i> , 2022, 5, 1864-1872.	5.0	7
116	Optimal configuration for the dual rotating-compensator Mueller matrix ellipsometer. , 2013, , .		6
117	Effect of cation and anion defects on the resistive switching polarity of ZnO x thin films. <i>Applied Physics A: Materials Science and Processing</i> , 2014, 114, 847-852.	2.3	6
118	Robust overlay metrology with differential Mueller matrix calculus. <i>Optics Express</i> , 2017, 25, 8491.	3.4	6
119	Measurement configuration optimization for dynamic metrology using Stokes polarimetry. <i>Measurement Science and Technology</i> , 2018, 29, 054010.	2.6	6
120	Dynamic characteristics of nematic liquid crystal variable retarders investigated by a high-speed polarimetry. <i>Journal of Optics (United Kingdom)</i> , 2019, 21, 065605.	2.2	6
121	Characterization of Volume Gratings Based on Distributed Dielectric Constant Model Using Mueller Matrix Ellipsometry. <i>Applied Sciences (Switzerland)</i> , 2019, 9, 698.	2.5	6
122	An imbalance aware lithography hotspot detection method based on HDAM and pre-trained GoogLeNet. <i>Measurement Science and Technology</i> , 2021, 32, 125008.	2.6	6
123	On the limits of low-numerical-aperture imaging scatterometry. <i>Optics Express</i> , 2020, 28, 8445.	3.4	6
124	Nonuniform depolarization properties of typical nanostructures and potential applications. <i>Optics Letters</i> , 2020, 45, 1910.	3.3	6
125	Superachromatic polarization modulator for stable and complete polarization measurement over an ultra-wide spectral range. <i>Optics Express</i> , 2022, 30, 15113.	3.4	6
126	Fabrication of high aspect ratio microfiber arrays that mimic gecko foot hairs. <i>Science Bulletin</i> , 2012, 57, 404-408.	1.7	5



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127	Direct Tailoring the Si Substrate for Antireflection via Random Nanohole Nanoimprint. Journal of Nanoscience and Nanotechnology, 2015, 15, 1297-1303.	0.9	5
128	Improved nanostructure reconstruction by performing data refinement in optical scatterometry. Journal of Optics (United Kingdom), 2016, 18, 015605.	2.2	5
129	Diffraction based single pulse measurement of air ionization dynamics induced by femtosecond laser. Optics Express, 2021, 29, 18601.	3.4	5
130	Multiobjective optimization for target design in diffraction-based overlay metrology. Applied Optics, 2020, 59, 2897.	1.8	5
131	Attitude metrology based on the field-of-view effect of birefringence using high-speed polarimetry. Optics Letters, 2020, 45, 2074.	3.3	5
132	Wide field-of-view angle linear retarder with an ultra-flat retardance response. Optics Letters, 2019, 44, 3026.	3.3	5
133	Stability analysis of the rolling process and regenerative chatter on 2030 tandem mills. Proceedings of the Institution of Mechanical Engineers, Part C: Journal of Mechanical Engineering Science, 2002, 216, 1225-1235.	2.1	4
134	Fast Evaluation of Aberration-Induced Intensity Distribution in Partially Coherent Imaging Systems by Cross Triple Correlation. Chinese Physics Letters, 2011, 28, 104212.	3.3	4
135	A single-image method of aberration retrieval for imaging systems under partially coherent illumination. Journal of Optics (United Kingdom), 2014, 16, 072001.	2.2	4
136	Sparse nonlinear inverse imaging for shot count reduction in inverse lithography. Optics Express, 2015, 23, 26919.	3.4	4
137	Optical Scatterometry for Nanostructure Metrology. Precision Manufacturing, 2019, , 477-513.	0.1	4
138	Dependence-Analysis-Based Data-Refinement in Optical Scatterometry for Fast Nanostructure Reconstruction. Applied Sciences (Switzerland), 2019, 9, 4091.	2.5	4
139	Thickness Scaling Effects on the Complex Optical Conductivity of Few-Layer WSe <sub>2</sub> Investigated by Spectroscopic Ellipsometry. Advanced Photonics Research, 2022, 3, .	3.6	4
140	Femtosecond laser induced damaging inside fused silica detected by a single-pulse ultrafast measurement system. Optics Express, 2022, 30, 26111.	3.4	4
141	Characterization of pixelated nanogratings in 3D holographic display by an imaging Mueller matrix ellipsometry. Optics Letters, 2022, 47, 3580.	3.3	4
142	Data Analysis Method for MEMS Dynamic Characterization Based on Stroboscopic Interferometer System. , 2007, , .		3
143	Computational lithography and computational metrology for nanomanufacturing. , 2011, , .		3
144	Fast aerial image simulations using one basis mask pattern for optical proximity correction. Journal of Vacuum Science and Technology B:Nanotechnology and Microelectronics, 2011, 29, 06FH03.	1.2	3

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145	Metal-Catalyst-Free Synthesis and Characterization of Single-Crystalline Silicon Oxynitride Nanowires. <i>Journal of Nanomaterials</i> , 2012, 2012, 1-8.	2.7	3
146	Pixel-based inverse lithography using a mask filtering technique. <i>Proceedings of SPIE</i> , 2013, , .	0.8	3
147	Polarization multiplexed all-dielectric metasurfaces for wavefront manipulation in a transmission mode. <i>Journal of Optics (United Kingdom)</i> , 2017, 19, 105102.	2.2	3
148	Reduced-basis boundary element method for fast electromagnetic field computation. <i>Journal of the Optical Society of America A: Optics and Image Science, and Vision</i> , 2017, 34, 2231.	1.5	3
149	Dynamic modulation performance of ferroelectric liquid crystal polarization rotators and Mueller matrix polarimeter optimization. <i>Frontiers of Mechanical Engineering</i> , 2020, 15, 256-264.	4.3	3
150	Optimal Design of High-Aspect-Ratio Micro/Nano Hierarchical Structures Mimicking Gecko Foot-Hairs. <i>Advanced Science Letters</i> , 2011, 4, 1546-1551.	0.2	3
151	Nondestructive detection of nano grating by generalized ellipsometer. <i>Wuli Xuebao/Acta Physica Sinica</i> , 2014, 63, 039101.	0.5	3
152	Multi-objective collaborative optimization strategy for efficiency and chromaticity of stratified OLEDs based on an optical simulation method and sensitivity analysis. <i>Optics Express</i> , 2020, 28, 27532.	3.4	3
153	Analytical modeling of wetting dependence on surface nanotopography. <i>Thin Solid Films</i> , 2010, 519, 1387-1390.	1.8	2
154	Comment on "Three-dimensional imaging of a phase object from a single sample orientation using an optical laser". <i>Physical Review B</i> , 2012, 86, .	3.2	2
155	Photonic crystal structures on nonflat surfaces fabricated by dry lift-off soft UV nanoimprint lithography. <i>Journal of Micromechanics and Microengineering</i> , 2013, 23, 125002.	2.6	2
156	Computational metrology for nanomanufacturing. <i>Proceedings of SPIE</i> , 2013, , .	0.8	2
157	Efficient representation of mask transmittance functions for vectorial lithography simulations. <i>Journal of the Optical Society of America A: Optics and Image Science, and Vision</i> , 2014, 31, B10.	1.5	2
158	Fast and accurate solution of inverse problem in optical scatterometry using heuristic search and robust correction. <i>Journal of Vacuum Science and Technology B: Nanotechnology and Microelectronics</i> , 2015, 33, .	1.2	2
159	Measurement errors induced by axis tilt of biplates in dual-rotating compensator Mueller matrix ellipsometers. , 2015, , .		2
160	Generalized measurement configuration optimization for accurate reconstruction of periodic nanostructures using optical scatterometry. , 2016, , .		2
161	Spectroscopic ellipsometry and X-ray diffraction studies on Si <sub>1-x</sub> Gex/Si epilayers and superlattices. <i>Applied Surface Science</i> , 2017, 421, 748-754.	6.1	2
162	Characterization of a liquid crystal variable retarder by Mueller matrix ellipsometry. , 2019, , .		2

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